

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Applicants : Zheng et al.

Serial No. : 10/790,492

Filed : March 1, 2004

Title: : **ATOMIC LAYER DEPOSITION OF CAPACITOR DIELECTRIC**

Docket No. : MIO 0082 N2/40509.292

Examiner : Thomas, Toniae M.

Art Unit : 2822

Conf. No. : 9512

**MAIL STOP RCE**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

EFS Web Electronic Submission

January 11, 2007

Sir or Madam:

**AMENDMENT WITH RCE**

This paper is being filed in response to the Office Action mailed October 11, 2006 in conjunction with a Request for Continued Examination. Reconsideration of the present application is respectfully requested in light of the amendments and remarks below, which include, in order of appearance, beginning on separate sheets:

- Amendments to the Claims; and
- Remarks.